

Message Text

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PAGE 01 OECD P 07356 241630Z

43

ACTION EB-07

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EXCON

E.O. 11652: XGDS1

TAGS: ESTC, COCOM

SUBJECT: COCOM LIST REVIEW - IL 1204 - ELECTRON BEAM

EQUIPMENT FOR THE DEPOSITION OF THIN FILM

REF: COCOM DOC REV (74) 1204/1

SUMMARY: DISCUSSION ON MARCH 20 FOUND THE US DEL DEFEND-
ING RETENTION OF IL 1204 AND RESERVING ON A LAST MINUTE
JAPANESE PROPOSAL FOR AN ADMINISTRATIVE EXCEPTIONS NOTE
FOR NON-AUTOMATIC, NON-CONTINUOUS ELECTRON
BEAM (EB) VACUUM (LENS) COATING EQUIPMENT WITHOUT DEPO-
SITION LAYER THICKNESS CONTROLS. ACTION REQUESTED: INAS-
MUCH AS 1204 COVERS EQUIPMENT PRIMARILY RELATED TO IL
1355, SEMICONDUCTOR MANUFACTURING EQUIPMENT, USDEL AND
WASHINGTON TEAM WOULD RECOMMEND CONSIDERATION OF DELE-
TION OF THE ITEM PROVIDED THAT SAID EQUIPMENT WOULD BE
COVERED BY IL 1355. END SUMMARY.

1. JAPAN SUBMITTED A PROPOSAL TO PLACE LENS COATING
EQUIPMENT UNDER AN. IN SUPPORT OF THEIR PROPOSAL, THE
JAPANESE NOTED THE ROUND ONE POSITIONS OF FRANCE AND THE
US, THE FORMER STATING THAT LENS COATING EQUIPMENT IS
NOT SUBJECT TO EMBARGO AND THE LATTER CLAIMING THAT IT IS-
JAPAN NOTED THAT LENS COATING IS CHARACTERIZED BY THE
FACT THAT IT IS NON-CONTINUOUS AND NON-AUTOMATIC EQUIP-
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PAGE 02 OECD P 07356 241630Z

MENT WITHOUT AUTOMATIC THICKNESS CONTROLS, IN CONTRAST

TO SEMICONDUCTOR AND THEIR FILM DEPOSITION EQUIPMENT WHICH POSSESSES THOSE FEATURES.

2. FRANCE RECALLED THAT EB VACUUM DEPOSITION EQUIPMENT FOR THIN FILM IS NOT COVERED BY 1204 BUT RATHER BY IL 1356 AS THEY HAD STATED IN DOC REV (71) 1204/14. GAMET NOTED THAT NOTE 2 WAS ADDRESSED TO THE COATING OF CAPACITORS PAPER AND 20 KILOVOLTS WAS SUFFICIENT FOR THAT PURPOSE. HE OBSERVED THAT JAPAN IS SEEKING LIBERALIZATION OF LESS SOPHISTICATED EQUIPMENT THAN OTHERS UNDER NOTE 2 AND SUGGESTED THAT THE JAPANESE INTEREST MIGHT BE SATISFIED BY AN AMENDMENT TO NOTE 2. CANADA PROPOSED DELETING THE WORDS "CONTINUOUS" AND "ROLL" FROM THE PRESENT NOTE 2 AS A MEANS OF ACCOMMODATING THE JAPANESE LENS COATING EQUIPMENT. JAPAN HAD TESTIFIED THAT IT IS PRACTICALLY IMPOSSIBLE TO CONVERT THE MANUAL LENS COATING EQUIPMENT TO AUTOMATIC OPERATION APPROPRIATE TO SEMICONDUCTOR MANUFACTURING. ALL DELS EXCEPT THE US, WHICH RESERVED, ACCEPTED THE AMENDMENTS TO NOTE 2.

3. THE UK NOTED THAT IT HAD ASKED THE US VIEW IN ROUND 1 ON WHETHER ANY EQUIPMENT IS COVERED IN 1204 WHICH WOULD NOT BE RELATED TO SEMICONDUCTOR MANUFACTURE, BUT AS YET HAD RECEIVED NO REPLY. SEVERAL TIMES THEREAFTER, THE UKDEL PRESSED THE US TO DESCRIBE WHAT IT BELIEVES TO BE COVERED BY 1204 AND WHY THAT EQUIPMENT COULD NOT BE COVERED BY 1355. FRANCE AND NETHERLANDS JOINED THE UK IN ITS QUESTIONING. THE USDEL WAS UNABLE TO REPLY BECAUSE THERE IS IN FACT NO COVERAGE IN 1204 WHICH IS NOT INCLUDED IN THE US PROPOSAL ON IL 1355. USDEL REPLIED THAT HE WOULD SEEK INSTRUCTIONS.

4. ACTION REQUESTED: INSTRUCTIONS TO LIFT THE US RESERVE ON DELETION ON IL 1204, WHICH OTHER DELS AGREE IS COVERED IN ANY CASE BY IL 1355 (C) AND WHICH IS SPECIFICALLY INCLUDED IN THE US PROPOSAL TO REVISE IL 1355.
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